

NEW MODEL

Fully-Automatic UV-LED Irradiation System

RAD-2020F/12



-  Selectable UV-light source
-  Reduced energy consumption
-  Improvement of UPH (+20%)
-  Reduced footprint



LINTEC Corporation

BENEFITS



Selectable UV-light source

RAD-2020F/12 can either be equipped with a high-pressure mercury lamp or a UV-LED system.

Note: the high-pressure mercury lamp machine version can be retrofitted with a UV-LED system later on.



Improvement of UPH (+20%)

UPH improvement of 20% compared to LINTEC's predecessor model by using electrified drive-shafts, as well as an optimized design-concept & process flow.

Maximum UPH: 110 wafers / h

⇒ 300mm wafer, UV irradiation speed 90mm/sec.



Reduced footprint

1,590mm(W) x 1,200mm(D) x 1,800mm(H)



Reduced energy consumption

Reduction of energy consumption by up to 95% with UV-LED and by up to 38% with high pressure mercury lamp.



COMPARISON: UV-LIGHT SOURCES

	High-pressure mercury lamp	UV-LED
Illuminance distribution	±10%	±5%
⇒ measured across ø of 300mm wafer		
Illumination setting	Fixed, 240mW/cm ²	Variable, 500-2500 mW/cm ²
UV-intensity	Direct setting, 50-500mJ/cm ²	Direct setting, 50-3000 mJ/cm ²
Wavelength	Peak of spectrum at 365nm	365nm only
Lifetime	~1,000h	~10,000h
Operation mode	Continuous, switch-off by standby timer	Only during UV-irradiation
Maintenance	In accordance with lifetime of lamp	Greatly reduced maintenance

REDUCED ENERGY CONSUMPTION

Compared to its predecessor, RAD-2010F/12, our latest model, RAD-2020F/12 reaches higher efficiency levels and helps to reduce consumption of valuable energy, regardless of which specification you choose.

UV-LED: Reduction by up to 95%

High-pressure mercury: Reduction by up to 38%

STANDARD SPEC & OPTIONS

RAD-2020F/12

Applicable Frame Sizes

ø300: SEMI Standard

ø200: DTF2-8-1

ø150: DTF2-6-1

Machine can be specified to handle a combination of two different frame sizes.

Loading Specs

Standard: Single cassette (8“,12“)

Options:

- Double cassette (8“,12“)
- EFEM-Unit with double load-port, 12“ only

Anti-ESD Speci- fication

Standard:

±100V or less within 10sec after the end of operation

Optional:

±50V or less immediately after the end of operation*

*Reference value, measured on mirror wafer

Temperature measure- ment

Contactless infrared measurement of workpiece temperature after UV irradiation

⇒ Optional for high-pressure mercury lamp machine version

OHT Capability

OHT (Overhead Hoist Transportation) and double load-port requirements can be supported by adding an EFEM (Equipment Front End Module) unit to the machine.



STANDARD

- Selectable UV-light source:
UV-LED or high-pressure mercury lamp
- Automatic size-change of transfer-arm for two different frame sizes
- FDC (Fault Detection and Classification)
- Anti-ESD specification:
 $\pm 100\text{V}$ or less within 10sec after the end of operation
- Direct setting of UV-light intensity by parameter (for UV-LED machine version only)



OPTIONS

- Workpiece temperature measurement after UV irradiation
- Automatic temperature-control system in the lamp house for the high-pressure mercury lamp machine version
- Double cassette loader or double load-port
- OHT capability
- High-class ESD countermeasure specification:
 $\pm 50\text{V}$ or less immediately after the end of operation*

*Reference value, measured on mirror wafer



Adwill

Tape x Equipment

Contact us.
We look forward
to meeting you!



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